The CiphercoN™ 1500 Fully Automated Outdoor Silane (SiH₄) Gas Cylinder Rack is representative of SDC’s continuous drive and commitment to providing the industry’s most reliable Ultra-High-Purity (UHP) specialty gas equipment available. Mass customization and modular design concepts of the gas panels & controls architecture have combined to widen the product configuration spectrum and greatly increase user flexibility.

From the Fab to the Lab to the University, SDC sets itself apart as the clear choice for value in today’s budget conscious environment.

Standard Configurations
- 2-cyl, [1-process, 1-purge]
- 2-cyl, [2-process], external purge source
- 3 cyl, [2-process, 1-purge]
- Independent out or autoswitchover

Standard Controls / Features
- PLC control of all critical functions
- Bright 10.4” color touch screen interface
- Proven auto-sequenced routines for all aspects of operations and maintenance
- User settable limits for all process and alarm parameters
- Exhaust pressure monitor
- On-screen warnings, alarms, prompting and instructions
- Emergency Off (EMO)
- EMO and EGO inputs
- Alarm outputs
- Multi-level password protection
- Diagnostics screen
- Valve cycle count screen
- Z-Purge ready for Class I Div II compliance
CiphercoN 1500™
Fully Automated Outdoor Silane Gas Rack

Large 10.4” color touch screen interface

The CiphercoN™ 1500 Outdoor Silane (SiH₄) Gas Cylinder Rack can also be configured as a Bulk Silane (SiH₄) Gas Delivery System which makes it simple to meet your exact gas delivery needs. The System is also CGA 13 Compliant. Our Modular Design Concept allows for component-level replacement, ease of service and upgradeability. Begin by choosing one of several “core” gas rack configurations. Start customizing right at the gas panel level with standard choices for regulator type, valve type, transducer ranges and purity level. Zero in further with a myriad of options like: purgeable splitters, RFO, filtration, purification, and many more. SDC's SPEC™ worksheet will walk you through this process in a simple, step-by-step manner. SDC Sales Engineers are always available to work through the customization process with you, either by phone, or in person.

OEM discounts and private-labeling services available.

FACILITIES REQUIREMENTS

<table>
<thead>
<tr>
<th>Requirement</th>
<th>Specification</th>
</tr>
</thead>
<tbody>
<tr>
<td>Pneumatic Supply</td>
<td>Adjustable to 90 psig</td>
</tr>
<tr>
<td>Process Purge</td>
<td>Adjustable to 80 psig</td>
</tr>
<tr>
<td>Vacuum Drive</td>
<td>Adjustable to 85 psig</td>
</tr>
<tr>
<td>Process Vent</td>
<td>&gt;1.0&quot; WC</td>
</tr>
<tr>
<td>Power</td>
<td>115V/3A</td>
</tr>
</tbody>
</table>

Process Panel Features
- Ultra-High-Purity (UHP) 316L SS or VAR construction
- Surface finish 10 Ra avg. or better
- Springless diaphragm valves
- Tied-diaphragm process regulator
- Precision flow sensor
- Vacuum assisted purging
- UHP orbitally welded with strategic VCR® breaks
- Helium leak tested to 1.0 x 10⁻⁹ atm*cc/s
- CLASS 100 / CLASS 10 cleanroom assembly and tested

Dimensions*
- 2 cyl. - 36"W x 83.25"H x 24"D
- 3 cyl. - 52"W x 83.25"H x 24"D
* Height dimensions include controller
Add 6.0” to width with cylinder heating option.

Code and Standards Referenced
- SME Section IX
- SEMI™ S2 Safety Guidelines for Semiconductor Manufacturing Equipment
- NFPA® 79, 496, 70 [NEC®]
- Factory Mutual®
- UL®
- CE®